

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE			ATTY. DOCKET NO. ONX-121	SERIAL NO. 09/891,760		
<b>LIST OF PRIOR ART CITED BY APPLICANT</b> (Use several sheets if necessary)			APPLICANT <b>Chuang-Chia Lin</b>			
			FILING DATE <b>June 25, 2001</b>		GROUP <b>2839</b>	
<b>AUG 24 2004</b> <b>U.S. PATENT DOCUMENTS</b>						
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>chl</i>	A 6,523,961	2/25/2003	Ilkov et al.	353	99	12/7/2000
<i>chl</i>	B 6498,870	12/24/2002	Wu et al.	385	18	4/20/1998
<i>chl</i>	C 6,114,044	9/5/2000	Houston et al.	428	447	5/30/1997
<i>chl</i>	D 5,512,374	4/30/1996	Wallace et al.	428	422	5/9/1994
<i>chl</i>	E 5,411,769	5/2/1995	Hornbeck	427	534	9/29/1993
<b>FOREIGN PATENT DOCUMENTS</b>						
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
						YES <input type="checkbox"/> NO <input type="checkbox"/>
<b>OTHER PRIOR ART</b> (Including Author, Title, Date, Pertinent Pages, Etc.)						
<i>chl</i>	F	R. Legtenberg et al., "Stiction of surface micromachined structures after rinsing and drying: model and investigation of adhesion mechanisms", Sensors and Actuators A, 43, pp 230-238, 1994				
<i>chl</i>	G	H. Guckel et al, "Fabrication of Micromechanical Devices from Polysilicon Films with Smooth Surfaces", Sensors and Actuators, 20, pp 117-122 (1989)				
<i>chl</i>	H	R. Alley et al, "The Effect of Release-Etch Processing on Surface Microstructure Stiction", Proc. IEEE Solid-State Sensor & Actuator Workshop, Hilton Head Island, S.C., pp. 202-207 (1992)				
<i>chl</i>	I	D. Kobayashi et al., "An Integrated Lateral Tunneling Unit" Proc. IEEE Micro Electro Mechanical Systems, Travemunde Germany, pp 214-219, (1992)				
<i>chl</i>	J	N. Takeshima et al. Proc. Int. Conf. Solid-State Sensors & Actuators (Transducers '91), San Francisco, CA, pp. 63-66, (1991, IEEE, New York))				
<i>chl</i>	K	C. Mastrangelo and C. Hsu, "Mechanical Stability and Adhesion of Microstructures Under Capillary Forces – Part I: Basic Theory" Journal of Microelectromechanical Systems, Vol. 2, No. 1 (March 1993) pp. 33-43				
<i>chl</i>	L	C. Mastrangelo and C. Hsu, "Mechanical Stability and Adhesion of Microstructures Under Capillary Forces – Part II: Experiments" Journal of Microelectromechanical Systems, Vol. 2, No. 1 (March 1993) pp. 44-55				
EXAMINER <i>Chasad</i>			DATE CONSIDERED <i>9/24/04</i>			

\* EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.